

<<表面和薄膜过程导论>>

图书基本信息

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内容概要

表面和薄膜科学是微电子、光电子和磁工业的物理基础，是现代技术进步的保证。在微观以至原子水平上研究和操纵表面让我们能够理解许多具有重要技术意义之器件的制作与运行。《表面和薄膜过程导论（第4版）》关注发生在表面和薄膜中的物理过程，详细介绍了与表面和薄膜相关的物理过程，包括热力学与运动学的理论基础，洁净表面的制备和表面的表征与分析技术，表面吸附与脱附过程，金属和半导体表面性质，外延生长和薄膜器件的表面过程等等内容。

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